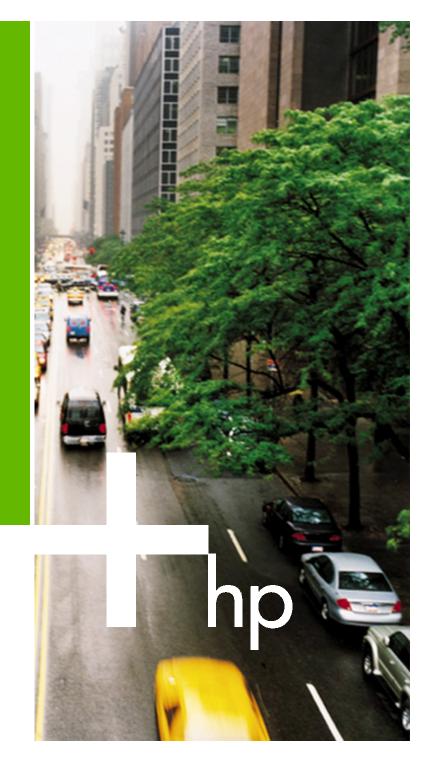


Nanoimprint lithography at Hewlett-Packard

William M. Tong Quantum Science Research, HP Labs (Palo Alto) Applied Molecular Systems, Inkjet Printing Platform (Corvallis) Hewlett Packard Company will.tong@hp.com

 $\ensuremath{^{\odot}}$ 2004 Hewlett-Packard Development Company, L.P.





Outline



- Overview of hp's portfolio in nanotechnology
- The problems with photolithography

• Why hp is interested in nanoimprint lithography

Nanotechnology research @ hp



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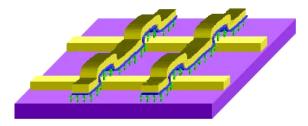
Quantum Science Research, Palo Alto Applied Molecular Sys., Corvallis

Dr. R. Stanley William	าร	Managers:	Ms. Susan Richards	
			Dr. Ken Abbot	
		Nanofabrication	Dr. James Stasiak Mr. Jim Ellenson	
			Mr. Tim Hostetler	
			Dr. Ken Kramer	
	ra		Dr. Kevin Peters	
Dr. Zhiyong Li	3		Dr. Jennifer Wu	
Dr. Ted Kamins			Dr. Qingqiao Wei	
Dr. Shashank Sharma			Dr. Tim Meyer	
Dr. Duncan Stewart		Chemistry:	Dr. Garry Hinch	
			Dr. Tom Etheridge	
		Electronic materials:		
			Dr. Randy Rannow	
Dr. Alexander Bratkovski Lawrence Berkeley National Lab				
Dr. Deirdre Olynick				
Dr. Alex Liddle				
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		Prof. F. Stoddart - Dept	. Chemistry & Biochem	
*Funding partly provided by DARPA			Prof. Yong Chen – Dept. Mech. Eng.	
Caltech				
2004Ž 9ž 21William M. TongProf. Jim Heath – Dept. Chemistry				
	Dr. William Tong Dr. Gun-Young Jung Dr. Wei Wu Dr. Saif Islam Ms. Xuema Li Mr. Douglas A. A. Ohlber Dr. Zhiyong Li Dr. Ted Kamins Dr. Shashank Sharma Dr. Duncan Stewart Mr. Phil Kuekes Mr. Greg Snider Mr. Warren Robinett Dr. Alexander Bratkovski	Dr. William Tong Dr. Gun-Young Jung Dr. Wei Wu Dr. Saif Islam Ms. Xuema Li Mr. Douglas A. A. Ohlberg Dr. Zhiyong Li Dr. Ted Kamins Dr. Shashank Sharma Dr. Duncan Stewart Mr. Phil Kuekes Mr. Greg Snider Mr. Warren Robinett Dr. Alexander Bratkovski	Dr. William Tong Dr. Gun-Young Jung Dr. Wei Wu Nanofabrication: Nr. Saif Islam Ms. Xuema Li Mr. Douglas A. A. Ohlberg Dr. Zhiyong Li Dr. Ted Kamins Dr. Shashank Sharma Dr. Duncan Stewart Mr. Phil Kuekes Mr. Greg Snider Mr. Warren Robinett Dr. Alexander Bratkovski Dr. Alexander Bratkovski Dr. Alex Liddle UCLA Prof. F. Stoddart - Dept Prof. Yong Chen - Dept Caltech	

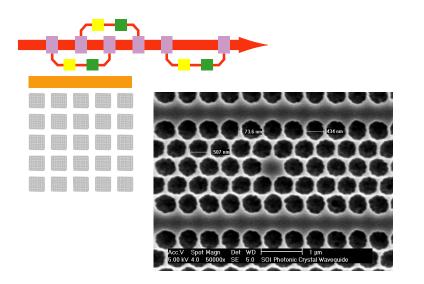
Areas of research for QSR



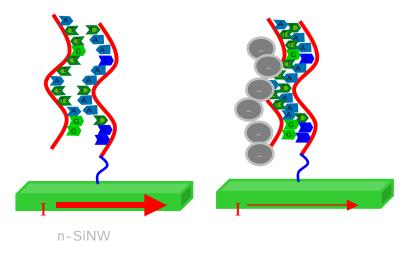
- Why go "nano"?
 - Because certain intrinsic properties of matter, e.g color, chemical reactivity, and electrical resistivity, depends strongly on the size and shape at the nanoscale.



Molecular electronics



c-ss-DNA

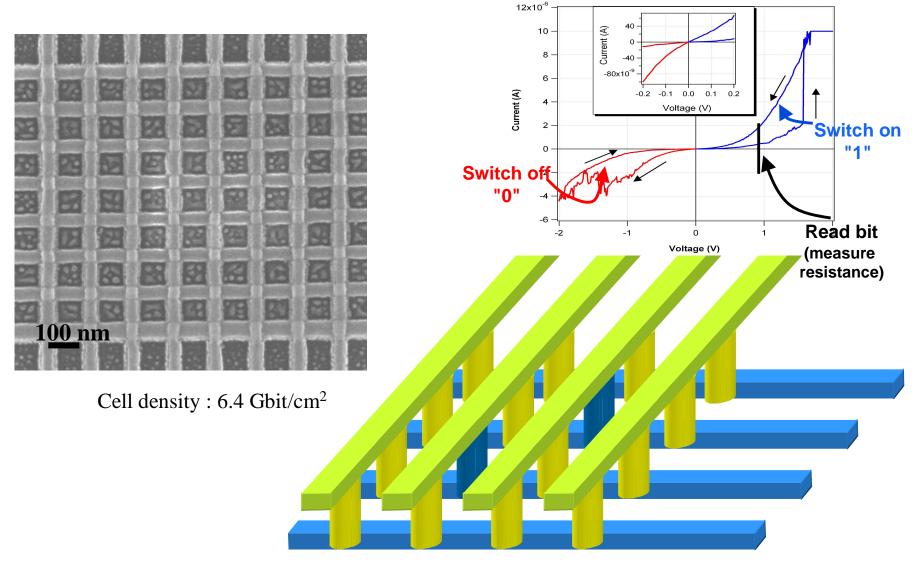


Photonics

Sensors

Nanoimprinted crossbar molecular switch memory

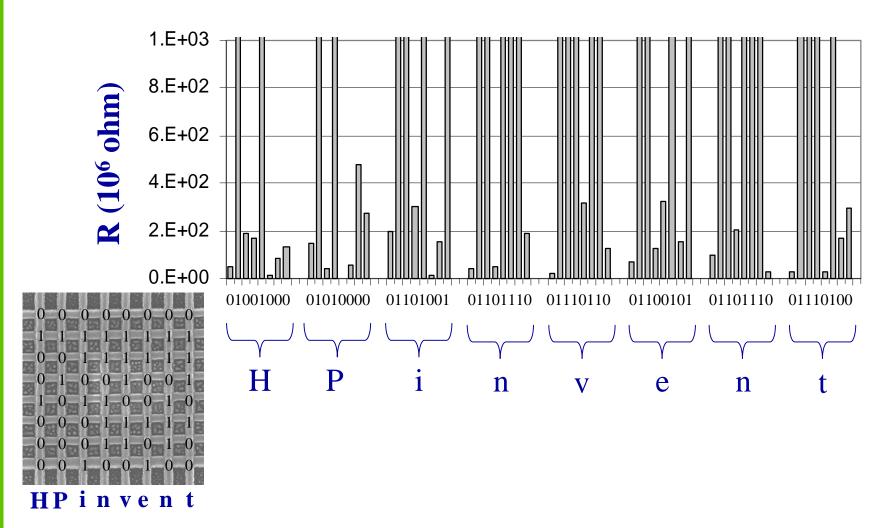




Y. Chen, G. Jung, et al. "Nanoscale molecular-switch crossbar circuits", Nanotechnology, 14, 462 (2003)



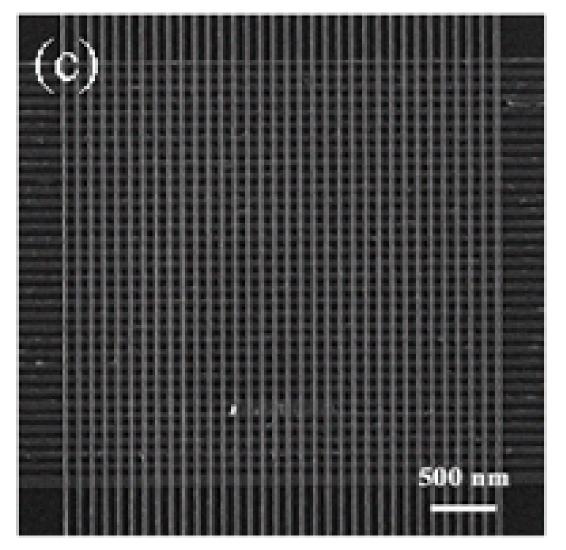




Y. Chen, G. Jung, et al. "Nanoscale molecular-switch crossbar circuits", Nanotechnology, 14, 462 (2003)



Sub-50 nm hp resolution achieved

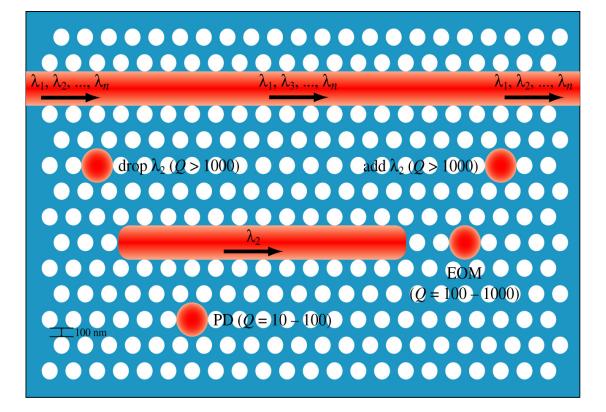


G. Y. Jung (HP Labs), to appear in Nano Letters

William M. Tong

Vision: Nanophotonic crystal waveguide for on board communications

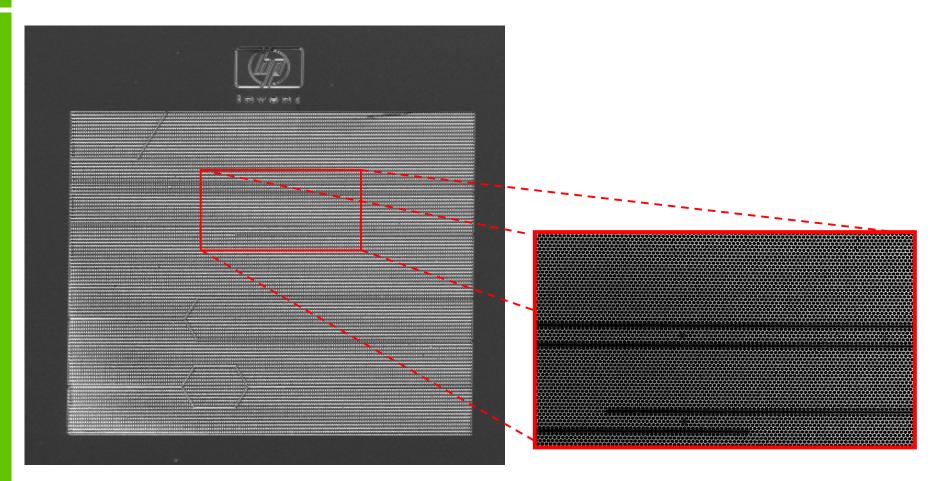




Advantages: üHigh speed üLow loss üCost effective

Photonic crystal waveguide successfully fabricated by nanoimprint lithography

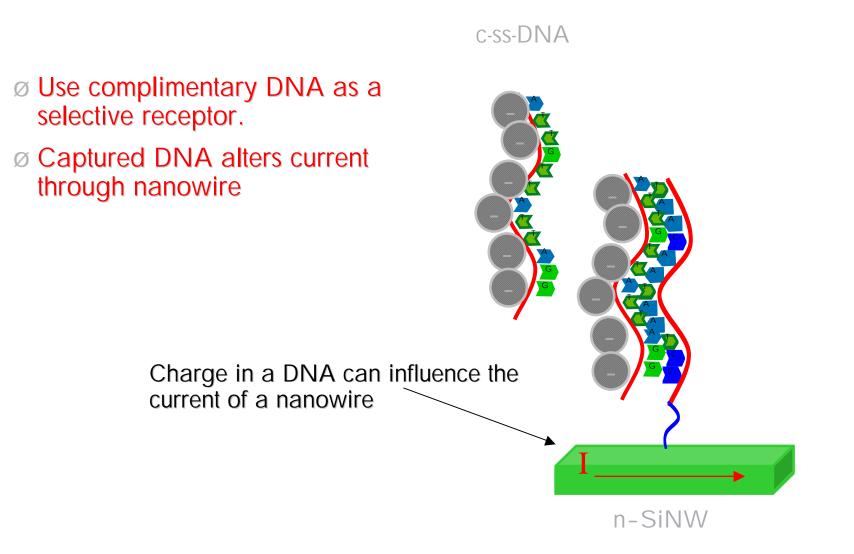




--Jim Ellenson, Tim Hostetler, Ray Beausoleil, Hewlett Packard

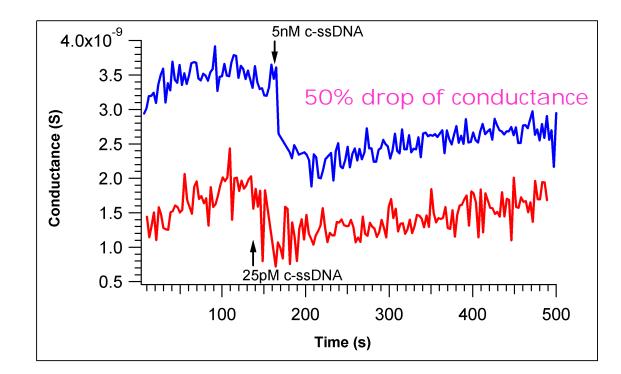
DNA identification sensor: toward single molecule detection



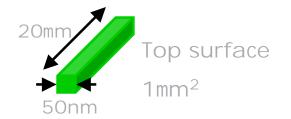


Successful sensing of DNA oligonucleotides on Si nanowire plateform





50nmn-Si Nanowire



Zhiyong Li, HPL

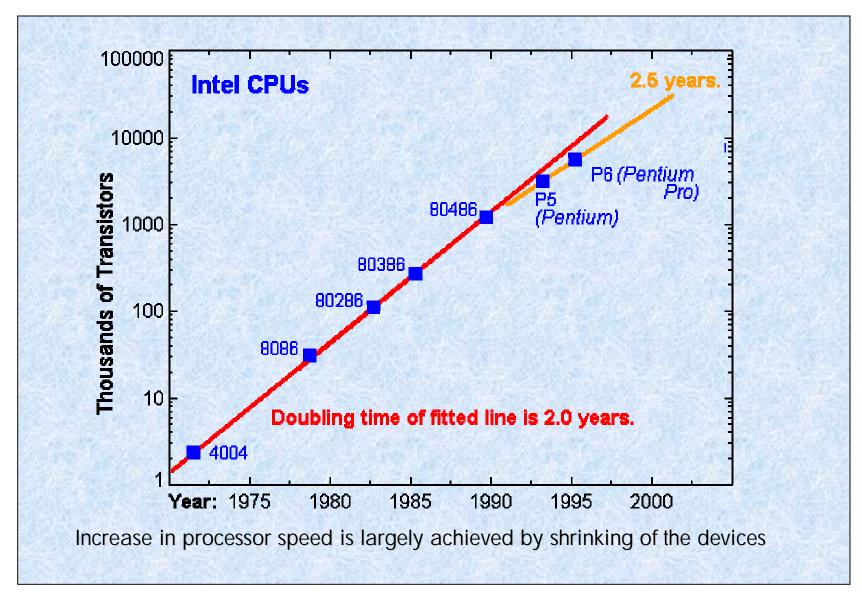
Why hp is interested in nanoimprint lithography?



- New applications emerging from nanotechnology research require lowcost, high volume manufacturing of nanoscale device
- Currently, inkjet cartridges are made with trailing edge photolithography (I-line 365 nm)
- Hp is not interested in making nanoimprinter. Our goal is to help enable the technology

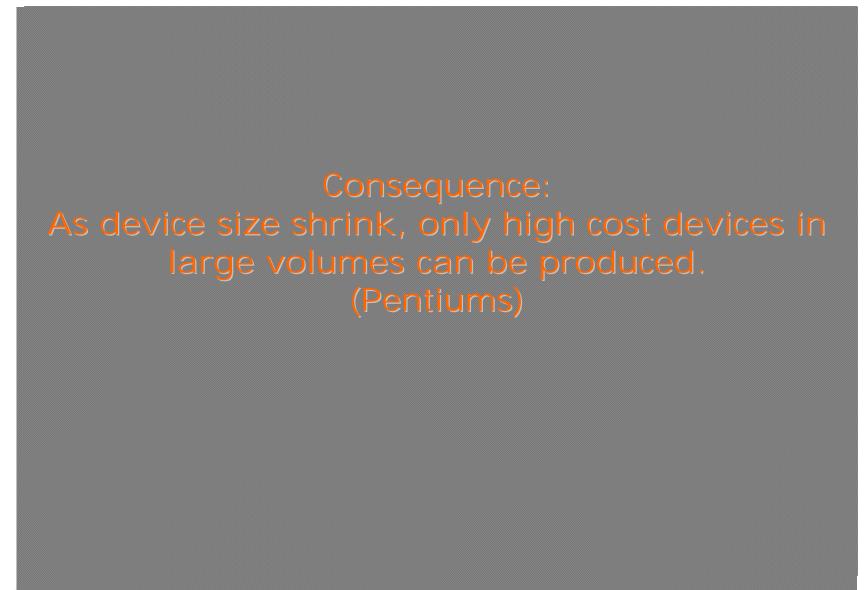


Moore's Law



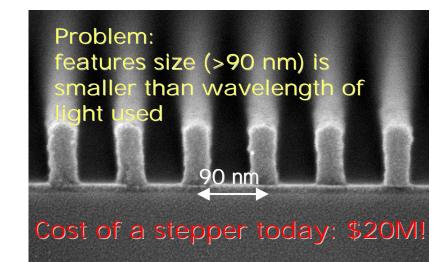
Moore's Second Law: Cost of a chip fab will double every two years

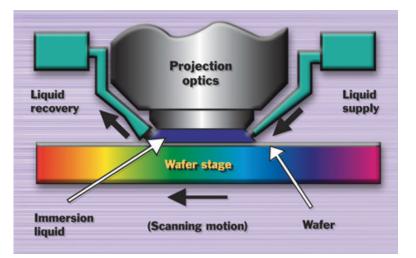




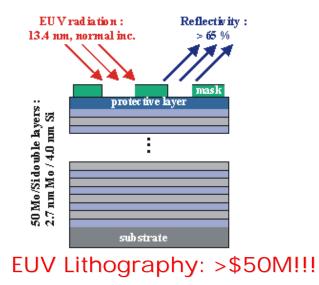


Photolithography is hitting a brick wall





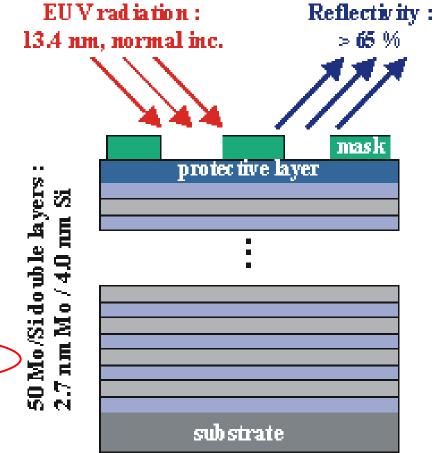
Immersion lithography: \$30M!!



Problem with EUVL: throughput

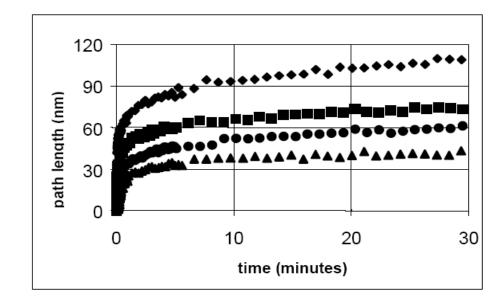


- Targetted for 32 nm node (Y2013)
- Uses 13 nm photons.
- Requires multilayer mask
- Issues
 - Defects on mask easy to print
 - A high power EUVL photon source is yet to be found.
 - Photons have high energy, therefore low countsà Line edge roughness.
 - Chemically-Amplified Resists are needed (CAR)





Acid diffusion limits linewidth to ~35 nm



Temperature dependence of acid path length in t-BOC. PAG #3 (10wt%) in reservoir layer. 75°C (\blacktriangle), 90°C (\bigcirc), 100°C (\blacksquare), 110°C (\diamondsuit)

Source: Postnikov, S. V. et al., " A study of rosolution limits due to intrinsic bias in chemically amplified photoresists," to appear in JVST B. (Grant Willson, UT Austin)



Key challenges in nanoimprint lithography

Alignment

- No expensive optics to take advantage of.
- Solution in development: Moire pattern
- Sub-pixel detection: 1/40 pixel (1 pixel ~ 100nm) feasible by commercial software e.g. Cognex

Mold patterning

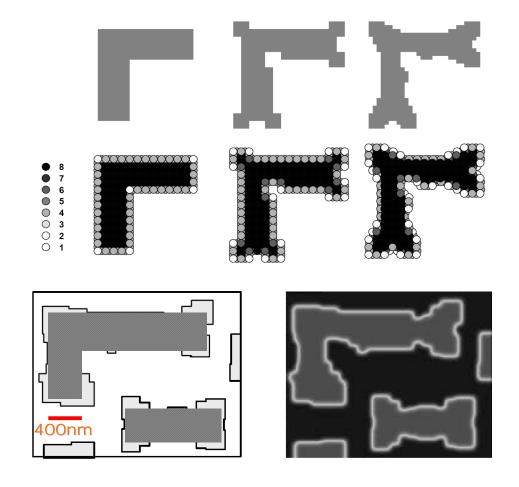
Mold is 1x instead of 4x as in current photomask

Patterning OPC features requires unprecedented accuracy on maskmaking



- Sub-wavelength printing puts a great burden on the mask patterning.
- OPC, Assist features, phase shift mask push cost
 - Current mask (90nm generation) cost >\$1M per set

Fine edge positioning



Source: T. Newman et al., "Evaluation of OPC mask printing with a raster scan pattern generation" (2002)

Jog

Assist feature

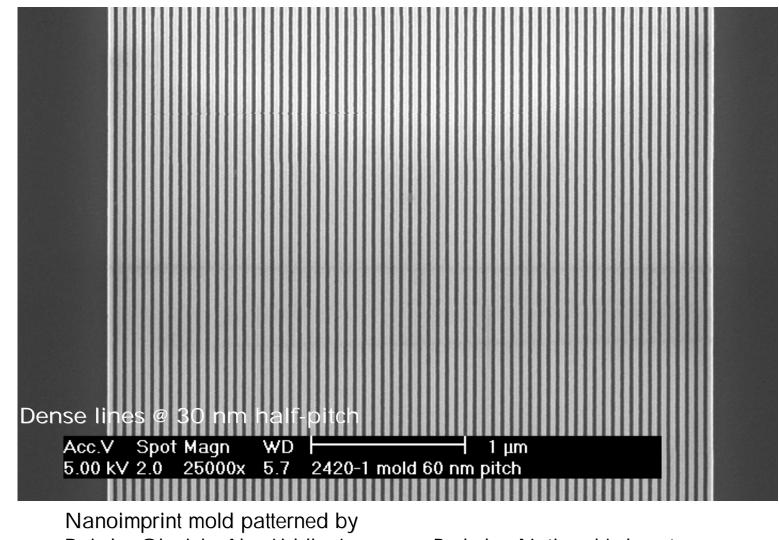
High aspect

ratio jog-

Corner



E-beam patterning can already achieve 30 nm hp



Deirdre Olynick, Alex Liddle, Lawrence Berkeley National Laboratory

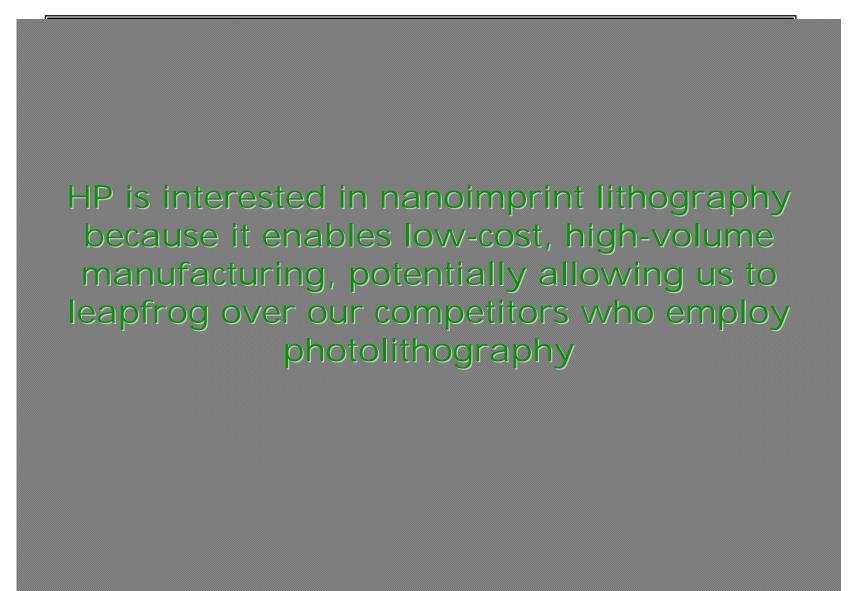
Nanoimprint lithography can achieve the same resolution as photolithography, but is much more cost-effective





Nanoimprint lithography is on the ITRS roadmap 2003 as an official NGL





Summary



- Overview of hp's portfolio in nanotechnology
 - Molecular electronics, photonics, sensors
 - All require low-cost nanoscale fabrication

• The problems with photolithography

- Cause: Features to be patterned are smaller than the wavelength of light used.
- Potential solutions will only get more expensive: only high cost devices can be fabricated. (Intel Pentiums)

• Why hp is interested in nanoimprint lithography

 A disruption technology that can provide low-cost, high tech solution to fabricate our nanoscale devices.



i n v e n t

Thank you!